		O-1449 (modified)	ATTY. DKT. NO. 5589-04001		SER	SERIAL NO. 10/679,857		
		ts and Publications ant's Information	APPLICANT: Stokowski et al.		GRO	GROUP: 2877		
		ure Statement						
(Use several sheets if necessary) FILING DATE: October 6, 2003								
U.S. PATENT DOCUMENTS								
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
MS OI	E	6466315	10/2002	Karpol et al.				
мя	(A	6268093	07/2001	Kenan et al.				
MS DEC 2	7 2005	6184976	02/2001	Park et al.		0		
MS PADE	É	6691052	02/2004	Maurer				
PADE	AAS							
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U.S. PATENT APPLICATION DOCUMENTS								
EXAM.	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
MS		2003/0207475	11/2003	Nakasuji et al.				
FOREIGN PATENT DOCUMENTS								
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO	
						<u></u>		
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
MS	E1 .	Barty et al., "Aerial Image Microscopes for the inspection of defects in EUV masks," Proceedings of SPIE, Vol. 4889, 2002, pp. 1073-1084.						
MS	E2	Yan et al., "Printability of Pellicle Defects in DUV 0.5 µm Lithography," SPIE Vol. 1604, 1991, pp. 106-117.						
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				····				

EXAMINER:

/Michael Stafira/

DATE CONSIDERED:

05/19/2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the pat nt owner.